

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
1	BRS	L2	12	piezoelectric adj3 (film or layer) same ion adj2 beam adj2 assist	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 11:15	
2	BRS	L3	1	"20020149019" and "lower electrode"	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 10:46	
3	BRS	L4	1120	piezoelectric adj3 ferroelectric	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 14:01	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
4	BRS	L5	0	piezoelectric adj3 ferroelectric same "ion beam" same "upper electrode" same "lower electrode"	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 10:49	
5	BRS	L6	0	piezoelectric adj3 ferroelectric same "ion beam" and "upper electrode" same "lower electrode"	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 10:49	
6	BRS	L7	8	piezoelectric same ferroelectric same "ion beam" and "upper electrode" same "lower electrode"	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 11:13	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
7	BRS	L8	2	piezoelectric same sol same dried same degreased same precursor same fired	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 11:15	
8	BRS	L9	2	piezoelectric same degreased same precursor same fired	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 11:15	
9	BRS	L10	2	piezoelectric same degreased same precursor and fired	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 11:15	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
10	BRS	L11	14	piezoelectric and electrode same ion adj2 beam adj2 assist	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 11:19	
11	IS&R	L12	0	(310/.\$.or29/25.35) .CC LS.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 11:19	
12	IS&R	L14	23056	((310/300-371,800) or (29/25.35)) .CCLS.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 14:01	
13	BRS	L15	9	114 and "ion beam" adj6 electrode	USPAT	2006/02/1 3 12:44	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
14	BRS	L16	1	114 and "ion beam" same contin\$5 adj2 deposit\$3	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 12:45	
15	BRS	L17	6	(piezoelectric or ferroelectric) and "ion beam" same contin\$5 adj2 deposit\$3	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 12:46	
16	BRS	L18	26	114 and irradiat\$3 adj2 substrate	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 12:53	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
17	BRS	L19	10	114 and irradiat\$3 adj2 substrate and ion adj1 beam	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 12:53	
18	BRS	L20	188	(piezoelectric or ferroelectric) and precursor and sol and fired	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 13:16	
19	BRS	L21	12	120 and degreas\$3	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 13:37	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
20	BRS	L22	1	120 and degreas\$3 and irradiat\$3	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 13:38	
21	BRS	L23	1	114 and pmn-pzt same compound\$1	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 14:03	
22	BRS	L25	4	114 and pmn-pzt	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 14:13	
23	IS&R	L26	1	("20030175062").PN.	US- PGPUB ; USPAT	2006/02/1 3 14:09	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
24	BRS	L27	2	114 and pmn-pzt and orient\$5	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 14:15	
25	BRS	L28	13	pmn-pzt and orient\$5	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:00	
26	BRS	L29	0	m2ruo4 and piezoelectric	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:00	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
27	BRS	L30	0	(CaRu04 or srRu04 or BaRu04) and piezoelectric	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:01	
28	BRS	L31	10	(CaRu03 or srRu03 or BaRu03) and piezoelectric	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:20	
29	BRS	L32	0	"20020149019" and irradiat\$3	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:27	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
30	BRS	L33	67	Ion adj3 (beam or assist) same continu\$3 adj3 deposit\$3	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:27	
31	BRS	L35	1	Ion adj3 (beam or assist) same continu\$3 adj3 deposit\$3 same piezoelectric	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:28	
32	BRS	L34	6	Ion adj3 (beam or assist) same continu\$3 adj3 deposit\$3 and piezoelectric	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:29	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
33	BRS	L36	1	Ion adj3 (beam or assist) same continu\$3 adj3 deposit\$3 and ferroelectric	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:32	
34	BRS	L38	3	Ion adj3 (beam or assist) same continu\$3 adj3 deposit\$3 same electrode	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:31	
35	BRS	L39	1	in-plane adj3 orient\$5 same continu\$3 adj3 deposit\$3 and (ferroelectric or electrode or piezoelectric)	US- PGPUB ; USPAT ; USOCR ; EPO; JPO; DERWE NT; IBM_T DB	2006/02/1 3 15:33	

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**Index Indication****Clear****Text Search**

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**Number Search****Applicant,Title of invention,Abstract — e.g. computer semiconductor**

If you use the AND/OR operation, please leave a SPACE between keywords.

One letter word or **Stopwords** are not searchable.

piezoelectric ferroelectric electrode

**OR****AND**

ion beam

**AND****AND**

continuous deposit

**AND****AND****Date of publication of application — e.g.19980401 - 19980405** - **AND****IPC — e.g. D01B7/04 A01C11/02**

If you use the OR operation, please leave a SPACE between keywords.

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# Searching PAJ

**MENU****NEWS****HELP**

## Search Results : 8

**Index Indication****Clear****Text Search**

If you want to conduct a Number Search, please click on  
the button to the right.

**Number Search**

### Applicant,Title of invention,Abstract — e.g. computer semiconductor

If you use the AND/OR operation, please leave a SPACE between keywords.

One letter word or **Stopwords** are not searchable.

piezoelectric ferroelectric electrode

**OR**

AND

in-plane

**AND**

AND

continuous deposit

**AND**

AND

### Date of publication of application — e.g. 19980401 - 19980405

 - 

AND

### IPC — e.g. D01B7/04 A01C11/02

If you use the OR operation, please leave a SPACE between keywords.

**Search****Stored data**

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**RESULT LIST**

0 results found in the Worldwide database for:

**method and piezoelectric** in the title AND **ion and beam and continuous and deposit** in the title or abstract  
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**RESULT LIST**

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**method** in the title AND **ion and beam and continuous and electrode** in the title or abstract  
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**1 ION BEAM PROCESSING METHOD AND PROCESSING DEVICE**

Inventor: TSUKIHARA MITSUKUNI; AMANO  
 YOSHITAKA; (+4)  
 EC: H01J37/30A4; H01J37/317A

Applicant: SUMITOMO EATON NOVA

IPC: H01J37/30; H01J37/317; H01J37/30 (+6)

Publication info: JP2003197144 - 2003-07-11

**2 ION IMPLANTATION APPARATUS AND ITS METHOD**

Inventor: AMAMIYA KENSUKE; TOKIKUCHI KATSUMI;  
 (+2)  
 EC:

Applicant: HITACHI LTD

IPC: H01J37/248; H01J37/317; H01L21/265 (+6)

Publication info: JP10261382 - 1998-09-29

**3 ELECTRON BEAM EXCITING NEGATIVE ION SOURCE AND NEGATIVE ION GENERATING METHOD**

Inventor: HARA TAMIO; HAMAGAKI MANABU; (+4)

Applicant: RIKAGAKU KENKYUSHO; KAWASAKI HEAVY IND LTD

EC:

IPC: G21B1/00; G21K1/00; H01J27/14 (+14)

Publication info: JP7142020 - 1995-06-02

**4 ION DETECTION METHOD IN ION TRAP MASS SPECTROMETER**

Inventor: JIEI KAATEISU SHIYUUOOTSU; JIYON  
 NEISAN ROORISU  
 EC: H01J49/42B2A

Applicant: FINNIGAN CORP

IPC: H01J49/42; H01J49/34; (IPC1-7): G01N27/62 (+1)

Publication info: JP6076790 - 1994-03-18

**5 METHOD FOR GENERATING PULSE ION BEAM**

Inventor: AKARI KOUICHIROU; KAWADA YUTAKA;  
 (+3)  
 EC:

Applicant: KOBE STEEL LTD

IPC: H01J27/08; H01J37/08; H01J27/02 (+3)

Publication info: JP6231709 - 1994-08-19

**6 METHOD AND SYSTEM FOR ELECTRON BEAM EXCITATION DRY ETCHING**

Inventor: WATABE HEIJI

Applicant: NIPPON ELECTRIC CO

EC:

IPC: H01L21/302; H01L21/02; (IPC1-7): H01L21/302

Publication info: JP5109675 - 1993-04-30

**7 Extraction grid for an ion source and method of manufacturing the same.**

Inventor: ENGEMANN JURGEN PROF DR  
 EC: H01J9/14; H01J27/02B; (+1)

Applicant: LEYBOLD HERAEUS GMBH & CO KG (DE)

IPC: H01J9/14; H01J27/02; H01J37/08 (+6)

Publication info: EP0230290 - 1987-07-29

**8 Method of operating storage tubes to compensate for positive ion charging**

Inventor:  
 EC: H01J31/18

Applicant: ENGLISH ELECTRIC VALVE CO LTD

IPC: H01J31/18; H01J31/18; (IPC1-7): H01J31/58

Publication info: GB2097994 - 1982-11-10

**9 INFORMATION STORAGE TUBE APPARATUS AND METHOD**

Inventor:  
 EC: H01J17/49D

Applicant: MONSANTO CO

IPC: H01J17/49; H01J17/49; (IPC1-7): H01J31/08 (+3)

Publication info: GB1309591 - 1973-03-14

**RESULT LIST**

5 results found in the Worldwide database for:

**method** in the title AND **plane and orientation and deposition and electrode** in the title or abstract  
(Results are sorted by date of upload in database)**1 PIEZOELECTRIC ELEMENT, LIQUID DISCHARGE HEAD AND MANUFACTURING METHOD FOR THEM**

Inventor: MURAI MASAMI; RI KINZAN

Applicant: SEIKO EPSON CORP

EC: B41J2/14D2; B41J2/16D2; (+5)

IPC: **B41J2/14; H01L41/24; B41J2/14** (+11)Publication info: **JP2004104066** - 2004-04-02**2 Method for preparing transparent and conducting sheets on polymers**

Inventor: HERRERO RUEDA JOSE (ES); GUILLEN

Applicant: CT DE INVESTIGACIONES ENERGETI (ES)

ARQUEROS CECILIA (ES)

EC: G02F1/1343B; H01B1/08; (+1)

IPC: **G02F1/1343; H01B1/08; H01L31/18** (+7)Publication info: **EP1367653** - 2003-12-03**3 SEMICONDUCTOR DEVICE AND METHOD OF MAKING IT**

Inventor: HIRONAKA MISAO (JP)

Applicant: MITSUBISHI ELECTRIC CORP (JP)

EC: H01L21/28; H01L23/482; (+1)

IPC: **H01L21/28; H01L23/482; H01L29/04** (+5)Publication info: **CA2057123** - 1992-07-09**4 Method for producing a MISFET and a MISFET produced thereby**

Inventor: WHITE JOHN CHARLES (GB); JANES TIMOTHY WILLIAM (GB)

Applicant: SECR DEFENCE (GB)

EC: H01L21/306B3; H01L21/336H6B; (+1)

IPC: **H01L21/306; H01L21/336; H01L29/423** (+4)Publication info: **GB2103013** - 1983-02-09**5 Method for producing a MISFET**

Inventor: JANES TIMOTHY W (GB); WHITE JOHN C (GB)

Applicant: SECR DEFENCE BRIT (GB)

EC: H01L21/28; H01L21/306B3; (+2)

IPC: **H01L21/28; H01L21/306; H01L21/336** (+5)Publication info: **US4453305** - 1984-06-12

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**RESULT LIST**

1 result found in the Worldwide database for:

**ferroelectric or piezoelectric** in the title AND **plane and orientation and deposition and electrode** in the title or at  
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**1 PIEZOELECTRIC ELEMENT, LIQUID DISCHARGE HEAD AND  
MANUFACTURING METHOD FOR THEM**

Inventor: MURAI MASAMI; RI KINZAN

Applicant: SEIKO EPSON CORP

EC: B41J2/14D2; B41J2/16D2; (+5)

IPC: **B41J2/14; H01L41/24; B41J2/14** (+11)

Publication info: **JP2004104066** - 2004-04-02

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Query :

Query: ((plane near orientation and deposition)) <AND> ( ( ferroelectric or piezoelectric ) <in> title )

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Query :

Query: ((plane near orientation and deposition)) <AND> ( ( (electrode and plane near orientation) ) <in> claims )

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### Search Results    02/13/2006 - 15:48:16

    Query :

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((ion near beam and deposition)) <AN|
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Query: ((ion near beam and deposition)) <AND> ( ( (ferroelectric or piezoelectric) ) <in> title ) <AND> ( ( (ion near beam) ) <in> claims )

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**Search Results** 02/13/2006 - 15:48:51

Query :

Query: ((plane near orientation and deposition)) &lt;AND&gt; ( ( ferroelectric or piezoelectric ) &lt;in&gt; title ) &lt;AND&gt; ( ( plane near orientation ) &lt;in&gt; claims )

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[Search Summary]

Results of searching in PCT (Full Text) for:

( piezoelectric or ferroelectric or electrode ) and ( ion near beam ) and ( continuous or continuously ) near ( deposit or depositing or deposition ): 4 records

Showing records 1 to 4 of 4 :

**Title**

1. (WO 01/67834) FLEXIBLE CIRCUITS WITH STATIC DISCHARGE PROTECTION AND PROCESS FOR MANUFACTURE
2. (WO 99/12404) FLEXIBLE CIRCUITS AND CARRIERS AND PROCESS FOR MANUFACTURE
3. (WO 99/04911) PYROLYTIC CHEMICAL VAPOR DEPOSITION OF SILICONE FILMS
4. (WO 98/20185) A PROCESS AND APPARATUS FOR DEPOSITING A CARBON-RICH COATING ON A MOVING SUBSTRATE

**Search Summary**

**piezoelectric NEAR deposit:** 15 occurrences in 14 records.

**ferroelectric NEAR deposit:** 16 occurrences in 15 records.

(piezoelectric NEAR deposit OR ferroelectric NEAR deposit): 29 records.

**electrode NEAR deposit:** 416 occurrences in 242 records.

((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit): 268 records.

**ion NEAR beam:** 37647 occurrences in 4480 records.

**ion NEAR deposit:** 131 occurrences in 84 records.

(ion NEAR beam AND ion NEAR deposit): 44 records.

((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND (ion NEAR beam AND ion NEAR deposit)): 0 records.

**continuous NEAR deposit:** 176 occurrences in 148 records.

**continuously NEAR deposit:** 51 occurrences in 44 records.

(continuous NEAR deposit OR continuously NEAR deposit): 188 records.

(((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND (ion NEAR beam AND ion NEAR deposit)) AND (continuous NEAR deposit OR continuously NEAR deposit)): 0 records.

**piezoelectric NEAR depositing:** 102 occurrences in 45 records.

**ferroelectric NEAR depositing:** 126 occurrences in 63 records.

(piezoelectric NEAR depositing OR ferroelectric NEAR depositing): 107 records.

**electrode NEAR depositing:** 1945 occurrences in 752 records.

((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing): 826 records.

**ion NEAR beam:** 37647 occurrences in 4480 records.

**ion NEAR depositing:** 323 occurrences in 153 records.

(ion NEAR beam AND ion NEAR depositing): 74 records.

((((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode

NEAR depositing) AND (ion NEAR beam AND ion NEAR depositing)): 0 records.

**continuous NEAR depositing:** 249 occurrences in 154 records.

**continuously NEAR depositing:** 92 occurrences in 63 records.

(continuous NEAR depositing OR continuously NEAR depositing): 212 records.

((((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing) AND (ion NEAR beam AND ion NEAR depositing)) AND (continuous NEAR depositing OR continuously NEAR depositing)): 0 records.

((((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND (ion NEAR beam AND ion NEAR deposit)) AND (continuous NEAR deposit OR continuously NEAR deposit)) OR (((((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing) AND (ion NEAR beam AND ion NEAR depositing)) AND (continuous NEAR depositing OR continuously NEAR depositing))): 0 records.

**piezoelectric NEAR deposition:** 140 occurrences in 77 records.

**ferroelectric NEAR deposition:** 185 occurrences in 64 records.

(piezoelectric NEAR deposition OR ferroelectric NEAR deposition): 141 records.

**electrode NEAR deposition:** 1978 occurrences in 983 records.

((piezoelectric NEAR deposition OR ferroelectric NEAR deposition) OR electrode NEAR deposition): 1094 records.

**ion NEAR beam:** 37647 occurrences in 4480 records.

**ion NEAR deposition:** 4688 occurrences in 1927 records.

(ion NEAR beam AND ion NEAR deposition): 1011 records.

((((piezoelectric NEAR deposition OR ferroelectric NEAR deposition) OR electrode NEAR deposition) AND (ion NEAR beam AND ion NEAR deposition)): 43 records.

**continuous NEAR deposition:** 728 occurrences in 460 records.

**continuously NEAR deposition:** 177 occurrences in 134 records.

(continuous NEAR deposition OR continuously NEAR deposition): 573 records.

((((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND (ion NEAR beam AND ion NEAR deposit)) AND (continuous NEAR deposit OR continuously NEAR deposit)) OR (((((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing) AND (ion NEAR beam AND ion NEAR depositing)) AND (continuous NEAR depositing OR continuously NEAR depositing))): 4 records.

(((((((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND (ion NEAR beam AND ion NEAR deposit)) AND (continuous NEAR deposit OR continuously NEAR deposit)) OR (((((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing) AND (ion NEAR beam AND ion NEAR depositing)) AND (continuous NEAR depositing OR continuously NEAR depositing))): 4 records.

Search Time: 10.2 seconds.



*Searching PCT (Full Text)...*

[Search Summary]

**Results of searching in PCT (Full Text) for:**

( piezoelectric or ferroelectric or electrode ) and ( "in plane" near orientation ) and  
 ( continuous or continuously ) near ( deposit or depositing or deposition ): 0 records

(piezoelectric or ferroelectric or electrode) and ("in pl

No records matching your query found in PCT (Full Text)

### Search Summary

**piezoelectric NEAR deposit:** 15 occurrences in 14 records.

**ferroelectric NEAR deposit:** 16 occurrences in 15 records.

(piezoelectric NEAR deposit OR ferroelectric NEAR deposit): 29 records.

**electrode NEAR deposit:** 416 occurrences in 242 records.

((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit): 268 records.

**"in plane" NEAR orientation:** 0 occurrences in 0 records.

**"in plane" NEAR deposit:** 0 occurrences in 0 records.

("in plane" NEAR orientation AND "in plane" NEAR deposit): 0 records.

((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND ("in plane" NEAR orientation AND "in plane" NEAR deposit)): 0 records.

**continuous NEAR deposit:** 176 occurrences in 148 records.

**continuously NEAR deposit:** 51 occurrences in 44 records.

(continuous NEAR deposit OR continuously NEAR deposit): 188 records.

((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND ("in plane" NEAR orientation AND "in plane" NEAR deposit)) AND (continuous NEAR deposit OR continuously NEAR deposit)): 0 records.

**piezoelectric NEAR depositing:** 102 occurrences in 45 records.

**ferroelectric NEAR depositing:** 126 occurrences in 63 records.

(piezoelectric NEAR depositing OR ferroelectric NEAR depositing): 107 records.

**electrode NEAR depositing:** 1945 occurrences in 752 records.

((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing): 826 records.

**"in plane" NEAR orientation:** 0 occurrences in 0 records.

**"in plane" NEAR depositing:** 0 occurrences in 0 records.

("in plane" NEAR orientation AND "in plane" NEAR depositing): 0 records.

((((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing) AND ("in plane" NEAR orientation AND "in plane" NEAR depositing)): 0 records.

**continuous NEAR depositing:** 249 occurrences in 154 records.

**continuously NEAR depositing:** 92 occurrences in 63 records.

(continuous NEAR depositing OR continuously NEAR depositing): 212 records.

((((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode

NEAR depositing) AND ("in plane" NEAR orientation AND "in plane" NEAR depositing)) AND (continuous NEAR depositing OR continuously NEAR depositing)): 0 records.

(((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND ("in plane" NEAR orientation AND "in plane" NEAR deposit)) AND (continuous NEAR deposit OR continuously NEAR deposit)) OR (((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing) AND ("in plane" NEAR orientation AND "in plane" NEAR depositing)) AND (continuous NEAR depositing OR continuously NEAR depositing))): 0 records.

**piezoelectric NEAR deposition:** 140 occurrences in 77 records.

**ferroelectric NEAR deposition:** 185 occurrences in 64 records.

(piezoelectric NEAR deposition OR ferroelectric NEAR deposition): 141 records.

**electrode NEAR deposition:** 1978 occurrences in 983 records.

((piezoelectric NEAR deposition OR ferroelectric NEAR deposition) OR electrode NEAR deposition): 1094 records.

**"in plane" NEAR orientation:** 0 occurrences in 0 records.

**"in plane" NEAR deposition:** 0 occurrences in 0 records.

("in plane" NEAR orientation AND "in plane" NEAR deposition): 0 records.

((((piezoelectric NEAR deposition OR ferroelectric NEAR deposition) OR electrode NEAR deposition) AND ("in plane" NEAR orientation AND "in plane" NEAR deposition)) OR electrode NEAR deposition): 0 records.

**continuous NEAR deposition:** 728 occurrences in 460 records.

**continuously NEAR deposition:** 177 occurrences in 134 records.

(continuous NEAR deposition OR continuously NEAR deposition): 573 records.

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((((((piezoelectric NEAR deposit OR ferroelectric NEAR deposit) OR electrode NEAR deposit) AND ("in plane" NEAR orientation AND "in plane" NEAR deposit)) AND (continuous NEAR deposit OR continuously NEAR deposit)) OR (((piezoelectric NEAR depositing OR ferroelectric NEAR depositing) OR electrode NEAR depositing) AND ("in plane" NEAR orientation AND "in plane" NEAR depositing)) AND (continuous NEAR depositing OR continuously NEAR depositing))) OR (((((piezoelectric NEAR deposition OR ferroelectric NEAR deposition) OR electrode NEAR deposition) AND ("in plane" NEAR orientation AND "in plane" NEAR deposition)) AND (continuous NEAR deposition OR continuously NEAR deposition)) OR electrode NEAR deposition): 0 records.

Search Time: 4.79 seconds.



Searching PCT (Full Text)...

[Search Summary]

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 and ( continuous or continuously ) near ( deposit or depositing or deposition ): 0  
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Search Time: 2.57 seconds.

